

Notice of References Cited	Application/Control No. 09/595,778	Applicant(s)/Patent Under Reexamination GRIMBERGEN ET AL.	
	Examiner Allan Olsen	Art Unit 1792	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-			
	B	US-			
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FOREIGN PATENT DOCUMENTS

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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Barna et al., In Situ Metrology, pages 35-44 of Chapter 22 of Handbook of Silicon Semiconductor Metrology, Edited by Alain Diebold, 2001(Marcel Dekker Inc)
	V	
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
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